Xi’an is the capital of Shaanxi province and is one of the most important cities in China. It is Chang’an in ancient times, the capital region for 13 dynasties. It was also the eastern end of the Silk Road.

**13th International Symposium on Measurement Technology and Intelligent Instruments (ISMTII-2017)**

Xi’an, Shaanxi, China
22-25 September, 2017

ISMTII-2017 will focus presenting scientific and engineering breakthroughs to develop the cutting-edge in modern measurement technologies and intelligent instruments. The Symposium offers the precious opportunity for experts and students to discuss the state-of-the-art in a diverse range of measurement fields. The exhibition and industrial forum are held to demonstrate the latest measurement technologies and instruments around the world.

**Organized by**
Xi’an Jiaotong University, China
Harbin Institute of Technology, China
HeFei University of Technology, China

**Important Dates**
Submission of abstracts: January 31, 2017
Notification of abstract acceptance: March 31, 2017
Submission of manuscripts of Full Papers: May 31, 2017
Notification of Full Paper acceptance: 15 June, 2017

**Honorary Chairs**
Prof. Zhu Li, China, China
Prof. Zhuxian Zhao, China

**Conference Chair**
Academ. Zhuangde Jiang, China

**Conference Co-Chair**
Prof. Jiubin Tan, China

**Organization Chair**
Prof. Shuming Yang, China

**Organization Co-Chair**
Prof. Liandong Yu, China
Prof. Jian Liu, China

**Symposium Scope (includes but not restricted to)**
- Micro and Nano Metrology
- In-process and Inline Metrology
- Management of Measurement Processes
- Optical Metrology
- Surface Metrology
- Automated Optical Inspection (AOI)
- Machine Vision and Image Processing
- Macro Metrology
- Intelligent Instruments for Automation
- Sensors and Actuators
- Calibration and Machine Tool Performance
- Material Characterization
- Education and Training in Metrology

**Registration Fees**
- Participants: 450USD
- Students: 300USD
- Accompanying Person: 200USD

**Publications**
- IOP and Springer will offer special issues for selected papers published on Advanced Manufacturing Technology (AMT) and Measurement Science and Technology (MST).
- Selected papers on nanometrology will also be recommended to submit to Surface Topography: Metrology and Properties, Nanomanufacturing and Nanometrology.

**Technical Tours**
- State Key Laboratory of Mechanical Manufacturing Systems Engineering
- The key laboratory of the Ministry of Education: Electronic Materials Research Laboratory